

Attorney Docket: 061063-0306825
Client Reference: OSP-15115



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re/PATENT APPLICATION of: Confirmation Number: 5650
SHIOTA ET AL.

Application No.: 10/706,266

Group Art Unit:

Filed: November 13, 2003

Examiner:

Title: SILICON WAFER AND MANUFACTURING METHOD THEREOF

PRELIMINARY AMENDMENT

Mail Stop Missing Parts
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Before beginning examination, please amend the above-identified application as follows: